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Dielectric Nanoantennas and Metasurfaces

Guest Editor:

Dr. Davide Rocco
Department of Information Engineering, University of Brescia, via Branze 38, 25123 Brescia, Italy

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Message from the Guest Editor

Dear Colleagues,

Dielectric nanoantennas have recently gained a lot of attention in many research areas, including sensing, solar cells, spectroscopy, and microscopy. The capability to excite either electric and magnetic multipolar resonances gives the possibility to shape the scattered light from such high-refractive-index structures in a desired manner. Moreover, they constitute the building blocks of the so-called metasurfaces.

Optical metasurfaces are 2D arrays of subwavelength scatterers designed to control properties of light ranging from its wavefront to polarization and intensity distribution or spectrum. The subwavelength resonators capture and re-emit the incident light. An appropriate geometrical choice of the dielectric nanoantennas that form the metasurface and of their mutual distance leads to the modification of the characteristics of light scattered from the 2D array. Thus, metasurfaces are attractive solutions in the miniaturization of bulk devices such as gratings, lenses, mirrors, holograms, waveplates, polarizers, and spectral filters.

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Editor-in-Chief

Prof. Dr. Nam-Trung Nguyen
Queensland Quantum and Advanced Technologies Research Institute, Griffith University, West Creek Road, Nathan, QLD 4111, Australia

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
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